



COPY OF PAPERS
ORIGINALLY FILED

8/1 Add
7/30/02
PATENT
81877.0007
[Signature]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Norikazu MIZUNO, et al.

Serial No: 09/670,917

Filed: September 29, 2000

For: SEMICONDUCTOR DEVICE
MANUFACTURING METHOD AND
APPARATUS FOR REMOVING SILICON
NITRIDE FORMED IN A REACTION
CONTAINER (AS AMENDED)

Art Unit: 2822

Examiner: GUERRERO, M

RECEIVED
JUL - 8 2002
A0800 MAIL ROOM

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:	
Commissioner for Patents Washington D.C. 20231, on	
June 20, 2002	
Date of Deposit	
Kimberly Yee	06/20/02
Name	Date
<i>Kimberly Yee</i>	
Signature	

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

This is in response to the Office Action dated December 20, 2001. Enclosed are a petition for a three-month extension of time and a check for the requisite fee, so that the period for response runs to and includes June 20, 2002. Please amend the above-referenced application as follows:

IN THE TITLE:

Please replace the title of the invention with the following text:

"SEMICONDUCTOR DEVICE MANUFACTURING METHOD AND
APPARATUS FOR REMOVING SILICON NITRIDE FORMED IN A REACTION
CONTAINER"